

ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

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Title of Invention	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER
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Submission Type : Information Disclosure Statement

Application Number:

10/680783



EFS ID: 90716

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First Named Applicant: William Jones

Attorney Docket Number:

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI04001-usidst.xml	1577	2005-08-17
us-ids	us-ids.dtd	7763	2005-08-17
us-ids	us-ids.xsl	12026	2005-08-17
package-data	SSI04001-pkda.xml	1706	2005-08-17
package-data	package-data.dtd	27025	2005-08-17
package-data	us-package-data.xsl	19263	2005-08-17
Total files size			69360

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